SHIMADZU
Excellence in Science

Microfocus X-Ray Inspection System

Xslicer SMX-6010

Seamless Fusion of
X-Ray Fluoroscopy and CT Imaging

Xslicer SMX-6010 is a planer X-ray inspection system, featuring a micro-focus X-ray generator and a 3 megapixel flat panel detector.

It delivers high-accuracy images with a wide dynamic range that enable detailed observations of internal structures and defects.

In addition, the system switches smoothly between fluoroscopy and Computed Tomography (CT), enabling a variety of observations matched to the shape of the sample.

This supports the inspection of various samples ranging from electronic parts with improved miniaturization to mounted boards with advances in high-density multilayer design.

Xslicer™ SMX-6010

Microfocus X-Ray Inspection System

High-Accuracy Imaging

High-accuracy images with a wide dynamic range are obtained thanks to the 3 megapixel flat panel detector and Shimadzu's unique HDR processing.

* HDR: High Dynamic Range

Simple Operation

Start fluoroscopic imaging in just three steps. With the simple UI, imaging can start easily regardless of the operator's experience level. A single button switches between fluoroscopy and CT. The imaging method can be switched easily to suit the sample.

Versatile, User-Friendly Functions

The Xslicer SMX-6010 features a Teaching Function and Stepwise Movement, enabling consecutive fluoroscopy and CT imaging, as well as a variety of measurement functions for numerical measurements of the images obtained. This supports inspections by operators and reduces the labor involved in inspections.

Contents

High-Accuracy Imaging

Equipped with a 3 Megapixel Flat Panel Detector

Detailed internal structure and defects can be revealed due to the 3 megapixel flat panel detector (2.3 times larger than previously).
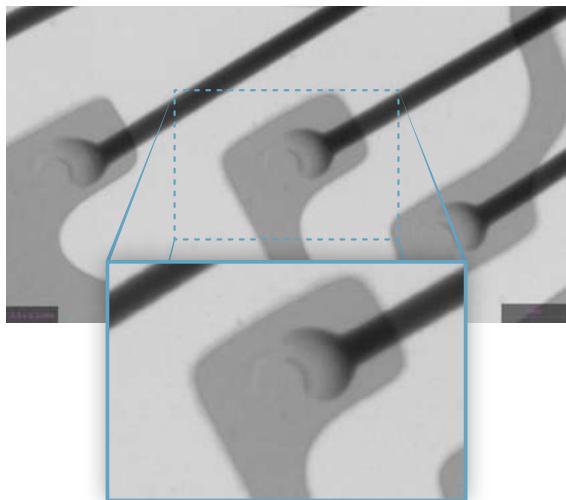

1.30 Megapixel Fluoroscopic Image
(Previous Shimadzu Instrument)
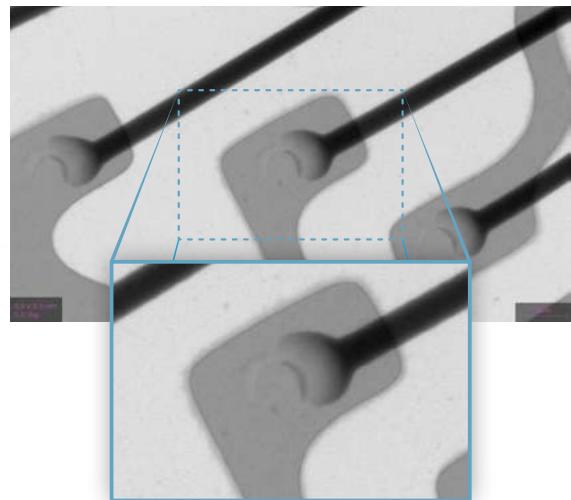
3 Megapixel Fluoroscopic Image

New HDR Processing Function

Shimadzu's unique, proprietary image processing technique/algorithm allows fluoroscopic images with a higher dynamic range, Regions that are both easy and difficult to penetrate can be observed at the same time, which shortens inspection times.

No HDR Processing

Bright regions are too bright.

Dark regions are too dark.

IC

HDR Processing

Both bright and dark regions are displayed with the appropriate contrast.
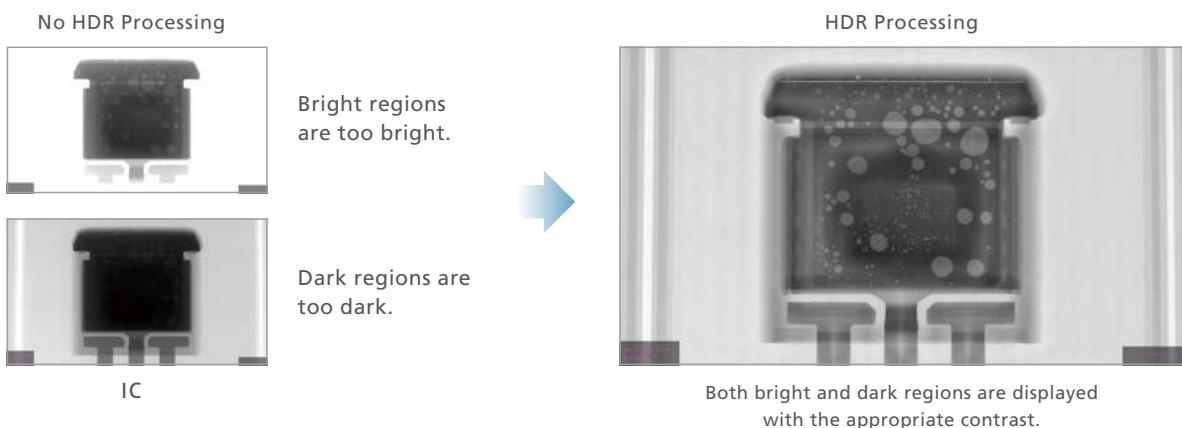
HDR Processing Application Example (Left: No HDR Processing; Right: HDR Processing)
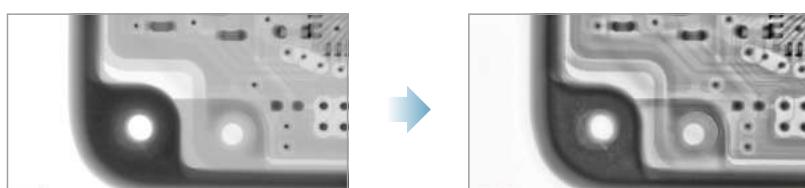
Sample: Electronic Control Unit

Simple Operation

Imaging in Three Steps

Fluoroscopic imaging in just three steps.
A large monitor screen and simple button layout provide excellent visibility for intuitive operation.
X-ray inspections are easy to perform, even for operators using the system for the first time.

Stage Positioning via the Live X-ray Image

Simply click on any position in the X-ray image to control all stage movements, such as changing the XY position, tilt, rotation, or field-of-view size.

Using Exterior Images for Stage Positioning

An observation camera provides a top-down view of the entire sample region. The user can alter the position of the sample using this top-down view. Just select a point of interest in the top-down view to accordingly move the stage. The image can be magnified to allow for fine positioning over individual components.

Positioning with a Mouse

All stage and manipulator positioning can be controlled using the mouse, allowing the operator to concentrate on examining the image on the monitor.

STEP 1
Change the sample.

Click the sample replacement button.
· X-ray emission stops.
· The stage automatically moves to a position where it is easier to replace the sample.

STEP 2
Start the inspection.

Close the front door and click [Start].
· X-rays are emitted.
· An exterior image of the entire stage area is captured.

STEP 3
Position the stage.

Click on the exterior image to roughly position the stage. Then click on the 2D X-ray live image to observe a position of interest.

## Xslicer SMX-6010

Simple Operation

Switch Smoothly between Fluoroscopy and CT

Switch between fluoroscopy and CT imaging by simply clicking on the menu tab.
The Xslicer SMX-6010 features tilted CT imaging. X-ray fluoroscopic images are captured and cross-sectional images are created by tilting the flat panel detector and rotating it 360 degrees. There is no need to install a separate unit for CT imaging.
The CT imaging scan conditions are easy to configure just by selecting the scan mode, scan angle, and scan region.
A region of interest in the fluoroscopic image can be observed immediately with a CT scan.

Fluoroscopic Image

Simply select the imaging conditions ([Simple], [Normal], or [Sharp]) and the imaging angle.
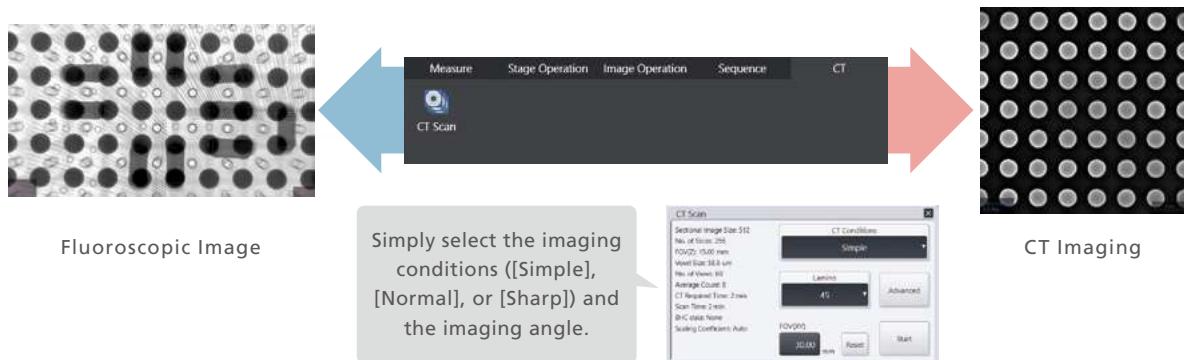
CT Imaging

## High-Speed Imaging and High-Speed Reconstruction

The calibration procedures are completely automated to speed up the imaging process.
Cross-sectional images can be displayed in as little as two minutes after CT imaging starts.

Xslicer SMX-6010 CT Imaging Sequence

Position the sample.

Imaging

Image reconstruction

Display

2 minutes

7.5 to 20 times higher throughput

Conventional CT Imaging Sequence

Position the sample.

Switch to the CT function

Calibration

Imaging

Image reconstruction

Display

15 to 40 minutes
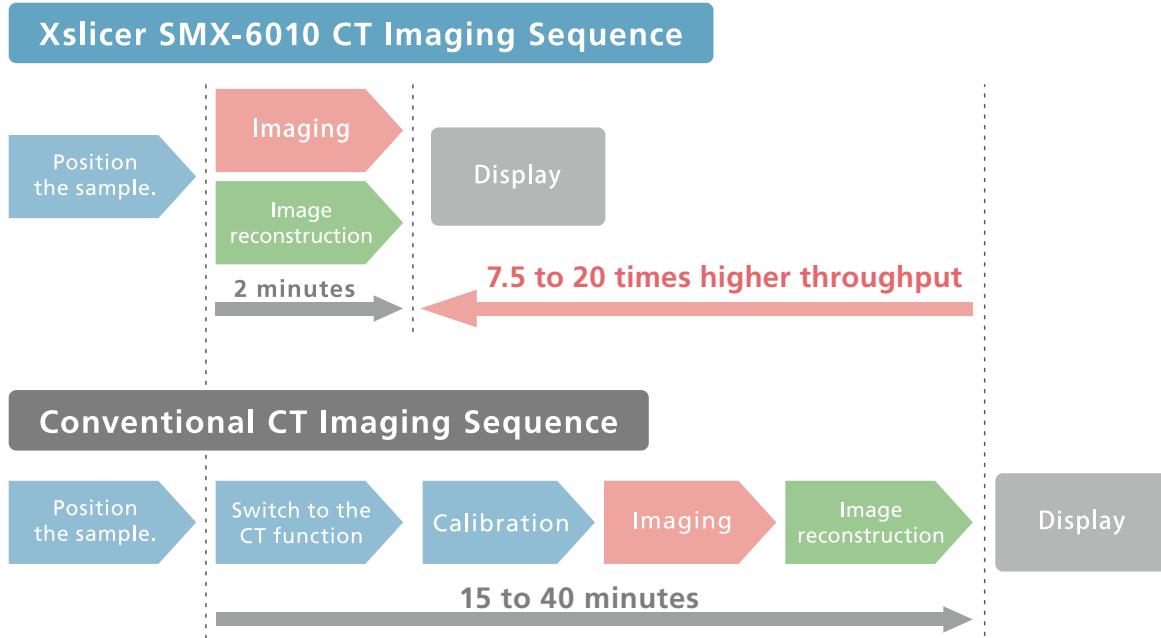
Wide CT Imaging Range

CT images can be obtained at any position within a 350 mm x 350 mm area. There is no need to move the sample to the center of the rotary table as in conventional tilted CT, allowing the scan to be positioned just by clicking on the scanning site.
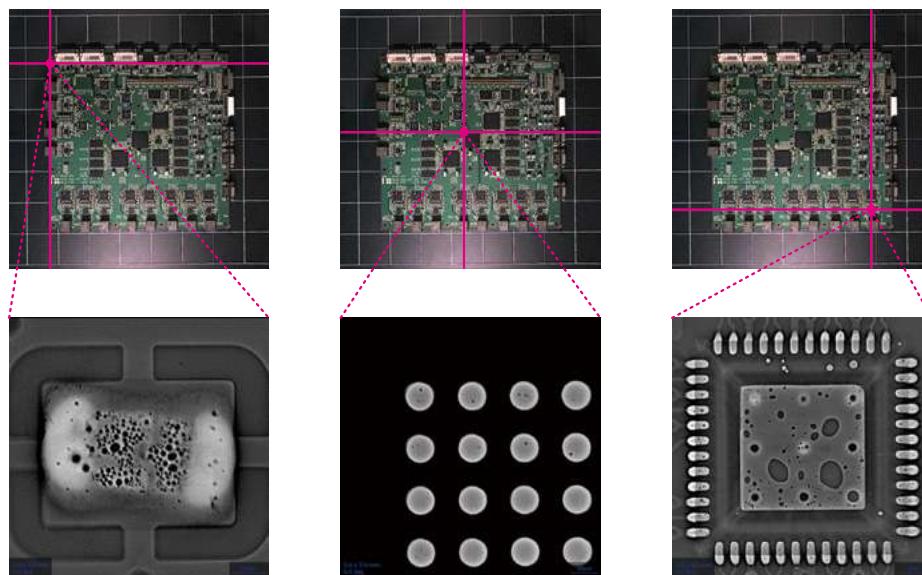
Set Tracking Points Easily

If a tracking point is set, the observation position of interest when tilted and rotated never leaves the center of the window. As a result, the point of interest is never lost.
To set a tracking point, simply tilt the detector and double click the position of interest.

Not tilted
(The point of interest is marked with a ○.)

Tilted

Tracking point settings value

Tracking ON
When tilted, the point of interest never leaves the center of the window because the stage tracks it.

Tilted

Tracking OFF
When tilted, the point of interest does not remain at the center of the window because the stage does not track it.
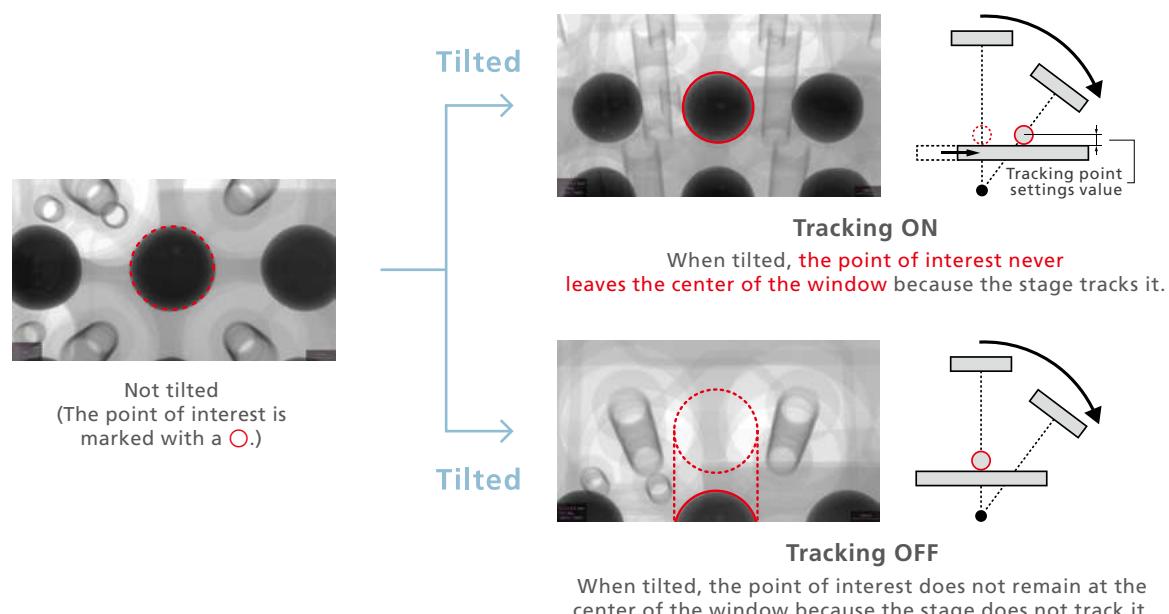
Versatile, User-Friendly Functions

Teaching Function

Fluoroscopic and CT imaging can be automated using the Teaching Function, which moves the sample stage to preregistered points of interest.
Additionally, for visual inspection, OK and NG judgment functions are included.

Point 1 (Fluoroscopic imaging)

Point 2 (CT imaging)

Point 3 (Fluoroscopic imaging)

Point 5 (Fluoroscopic imaging)

Point 4 (CT imaging)
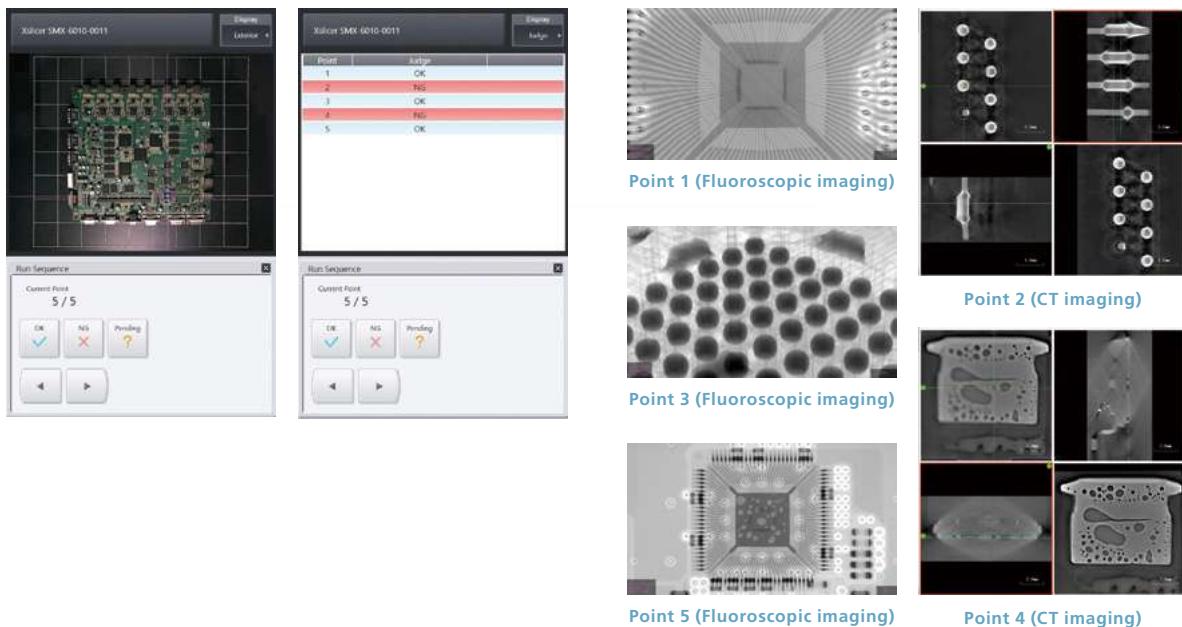
Stepwise Movement

The Stepwise Movement function moves the stage at constant intervals. It specifies the starting position, amount of movement, and number of movements. When this function is used, observations are performed while the stage makes consecutive movements from the starting position in accordance with the settings. Consecutive fluoroscopic or CT scans can be performed of samples arranged at set intervals.

Example of Consecutive CT Images of 25 Samples Aligned on a Pallet

ICs Aligned on a Pallet

Continuous CT scan possible (e.g., 25 scans)

Cross-Sectional Image

Determination Results

Exterior Image
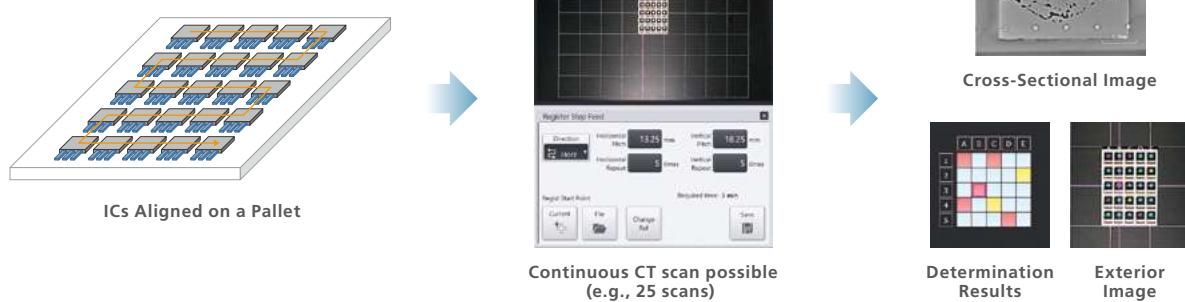
A list of the determination results is displayed when all the configured points have been inspected.

☐ : Pass   ☐ : Fail   ☐ : Defer

Selective measures can be performed after inspecting the results.

Panoramic Imaging Function

A wide-range fluoroscopic image can be obtained just by specifying the imaging span on the external image. An improved stitching process ensures there are no visible lines in the panoramic image where the individual images are joined. A fluoroscopic image up to 32 megapixels in size can be obtained.

300 mm

300 mm
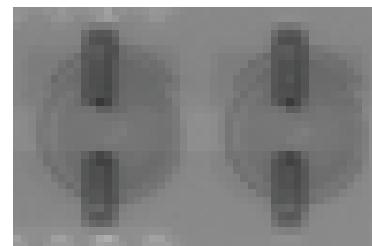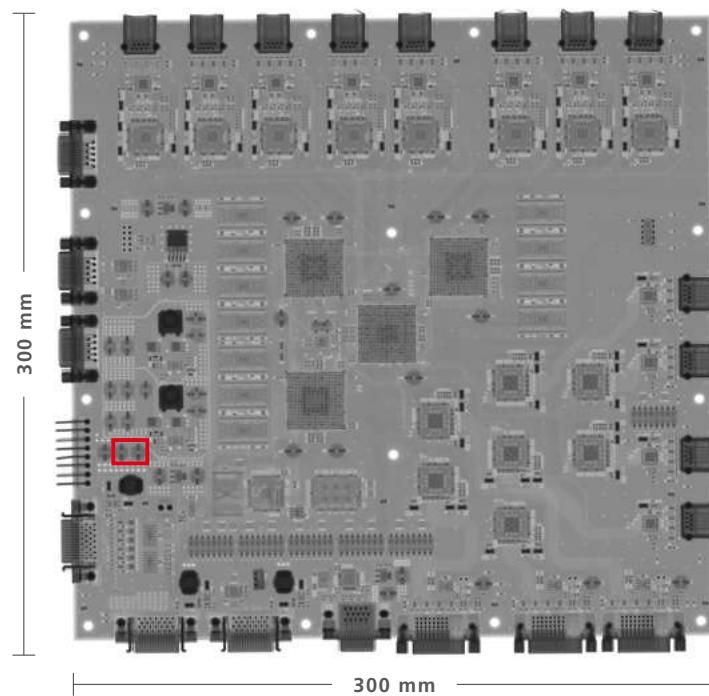
**2.23 Megapixel Panoramic Image without Stitching (Partially Enlarged) (Former Model)**
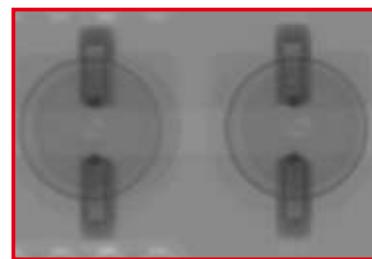
32 Megapixel Panoramic Image with Stitching (Partially Enlarged) (Xslicer SMX-6010)

Image Adjustment Functions (Auto Window Function and Region of Interest Function)

The contrast can be automatically optimized to make the area of interest easy to see. Normally, with this sort of optimization function, the part outside the region of interest becomes difficult to see. However, a proprietary image processing algorithm automatically adjusts the image to ensure that the part outside the region of interest remains as easy to see as possible.

AW

Depending on the changing conditions, the optimal window level and window width are specified in real time.

ROI
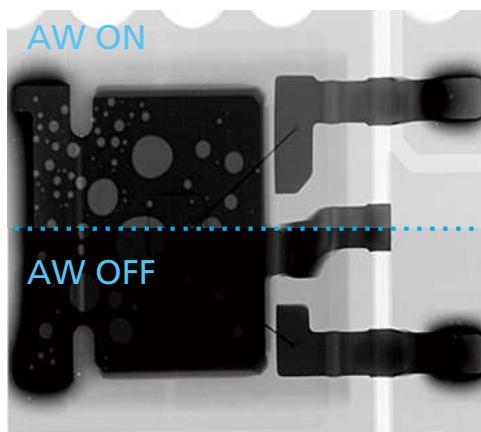
When selecting an area of interest, the window level and window width are optimized for the specified range.

AW ON

AW OFF

Area of Interest

Xslicer SMX-6010
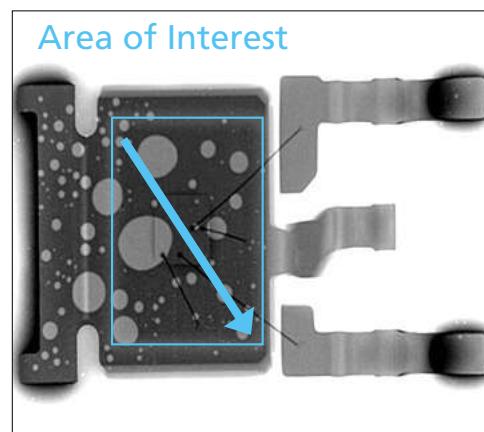
Versatile, User-Friendly Functions

Ball Grid Array (BGA) Measurements

BGA bump diameters and void ratios can be measured.
With our proprietary image processing algorithm, complicated parameter settings are unnecessary.*
Multiple settings can be saved and applicable ones can be accessed for each inspection target prior to measurement.
* Manual adjustments may be required depending on the sample.

(Measurable Items)
- Total void ratio
- Maximum void ratio
- Bump diameter
- Bump roundness

Area Ratio Measurements

Die bonds, solder paste wettability, and other area ratios can be measured.
The parameter settings are not required thanks to Shimadzu's proprietary image processing algorithm.*
It is also possible to save multiple settings, and then call up the applicable settings for each inspection target prior to measurement. Furthermore, pass/fail determinations can be made based on the area ratio.
* Manual adjustments may be required depending on the sample.
* The measurement range (ROI) can be configured manually.
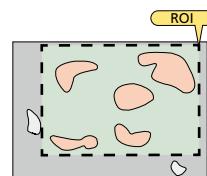
Static Image

Wire Sweep Ratio Measurements

The wire sweep ratio can be measured by specifying both ends of the bonding wire and the point of maximum curvature. Pass/fail determinations can be made depending on the wire sweep ratio.

Point of Maximum Curvature

Wire

L2

L1

Wire Sweep Ratio = L2/L1 × 100 (%)
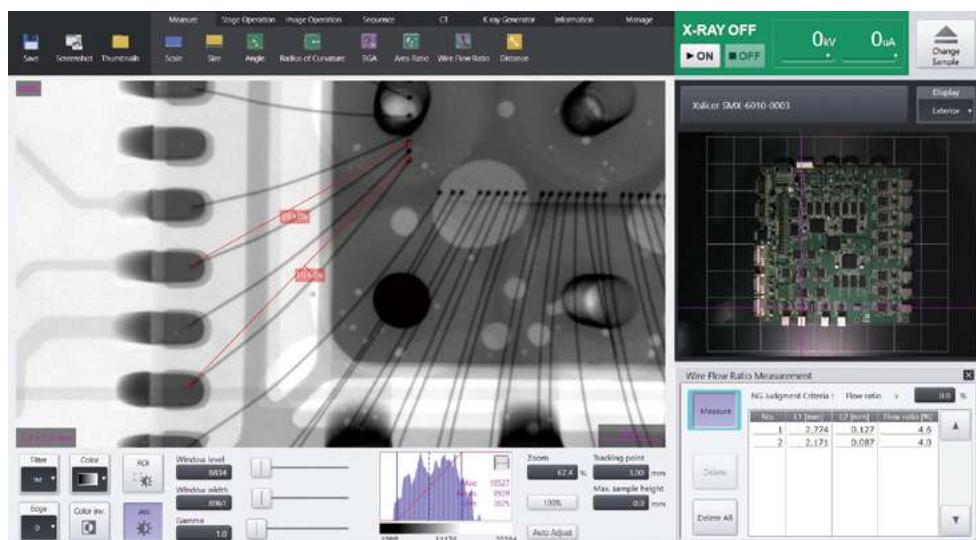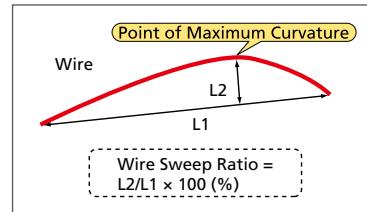
Dimension Measurements

The Xslicer SMX-6010 supports both 2-point distance and 3-point measurements.
With this system, sizes are measured efficiently by calculating calibration data internally in synchronization with the fluoroscopic magnification.
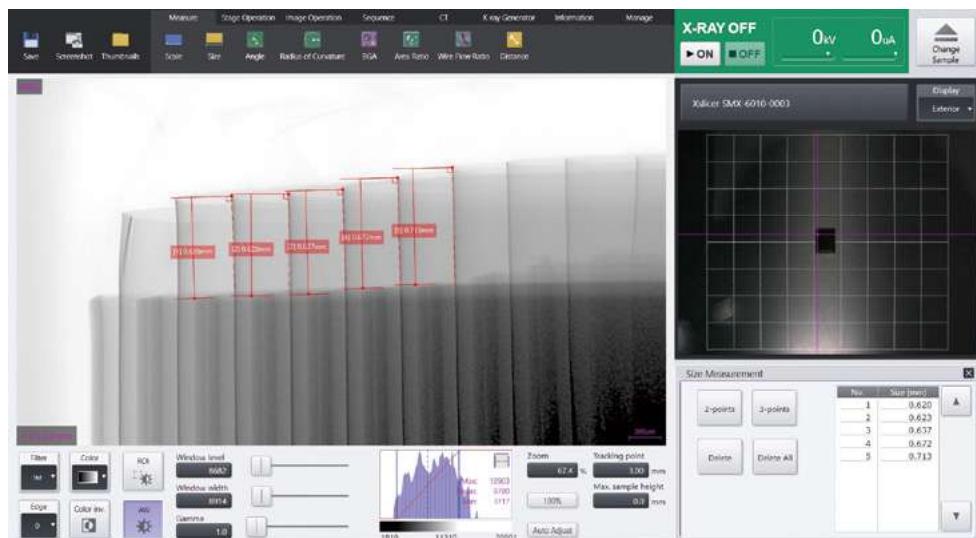
System Configuration

> ## An easy-to-maintain
> ## Shimadzu X-ray generator and various safety mechanisms
> ## reduce costs and ensure safe use.

X-Ray Generator

The Xslicer SMX-6010 features a160-kV open tube and can resolve down to 1 micron.
Due to the integrated high-voltage transformer, no greasing is necessary.
The filament replacement process is simplified by automatic adjustments.
Note: 1 μm resolution by JIMA chart analysis.

X-Ray Detector

Equipped with a 3 megapixel flat panel detector.
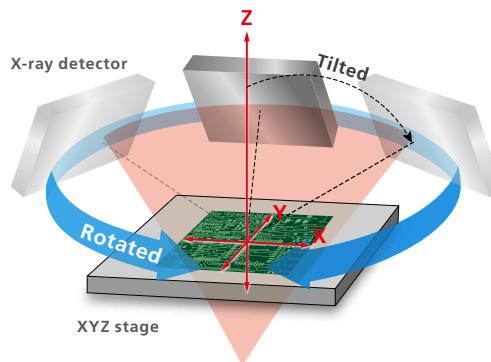
Five-Axis Stage

In addition to the X, Y, and Z axes of the sample stage,
the detector tilts and rotates.
Five-axis movement supports inspections from any angle.

X-Ray Shield Box

The X-rays are well shielded. (Maximum 1 μSv/h external X-ray leakage)
The front door lock mechanism prevents the front door from opening during X-ray emission.
The interlock mechanism also disables movement of the 5-axis stage when the door is open.

Collision Sensor

A collision sensor is provided around the X-ray detector to stop the Stage in the event of an emergency (a collision with the sample).

Utilities

System operation requires only the following: 200 V AC ± 10 %, 1.5 kVA (ground resistance 100 Ω max.)
There is no need to provide air or cooling water.

Principles and Features of Planer CT Imaging

Capable of Maximum Image Enlargement for Planer Samples

◼ Planer CT

X-ray detector

XY stage
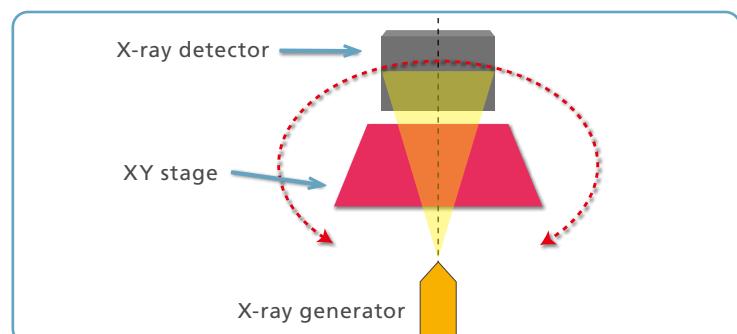
X-ray generator

Scanning large circuit boards with planer CT:

The sample is mounted on an XY stage, so it can approach the X-ray generator, enabling maximum image enlargement.

◼ Vertical CT

Obstructed

Rotary table

X-ray detector

X-ray generator

Maximum trajectory for the sample

Sample (Large substrate)

Vertical CT Viewed from above the Rotary Table
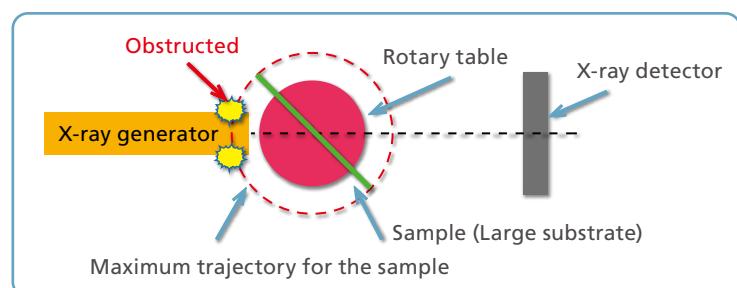
Scanning large circuit boards with vertical CT:

When the sample is brought near the X-ray generator to increase the magnification, it will be obstructed by the X-ray generator during CT imaging, making imaging at maximum magnification impossible.

Observation Examples

For samples like circuit boards with planer CT, images with a high magnification can be obtained, unlike with orthogonal CT, which is affected by the width of the sample.
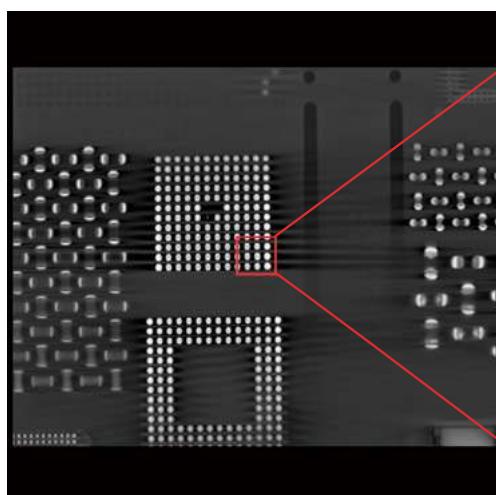
Vertical CT
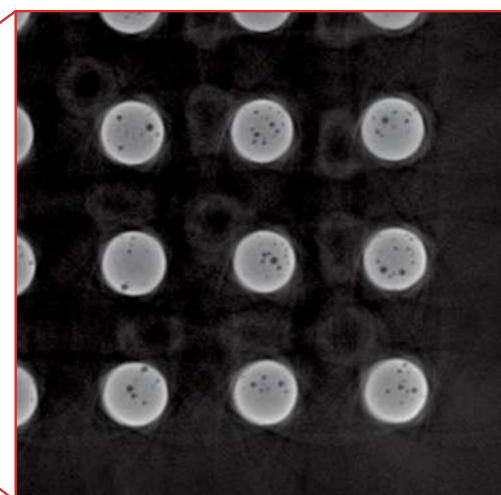
Xslicer SMX-6010

Applications

Ball Grid Array
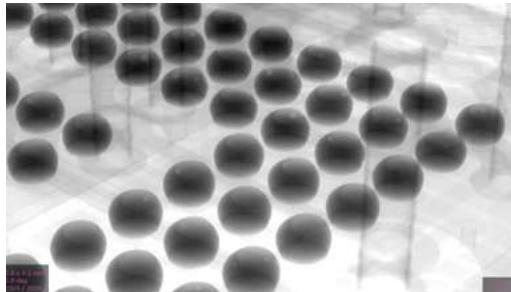
Fluoroscopic Image
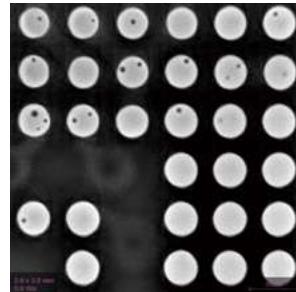
Cross-Sectional Image
Scanning Region = 3 mm
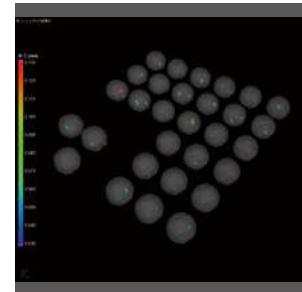
VR Image

Vehicle Mounted LED Lamp

Fluoroscopic Image
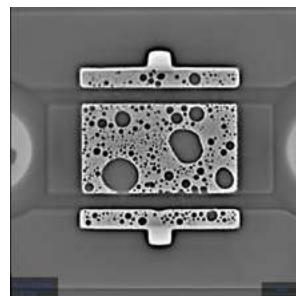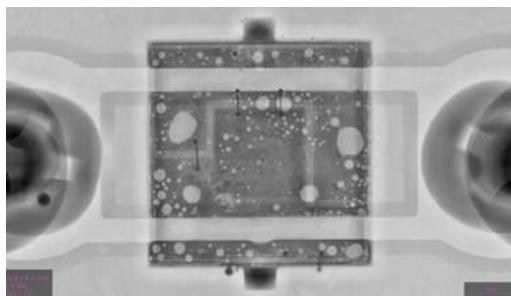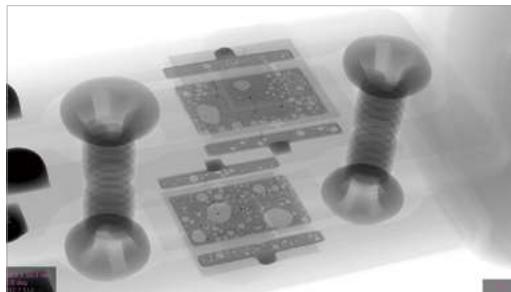

VR Image

Fluoroscopic Image
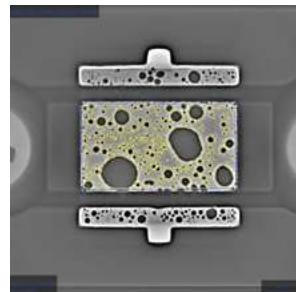
Top: Cross-Sectional Image
Scanning Region = 9 mm
**Bottom: Area Ratio Measurement**

Area Ratio
Measurement Results

Chip Capacitor
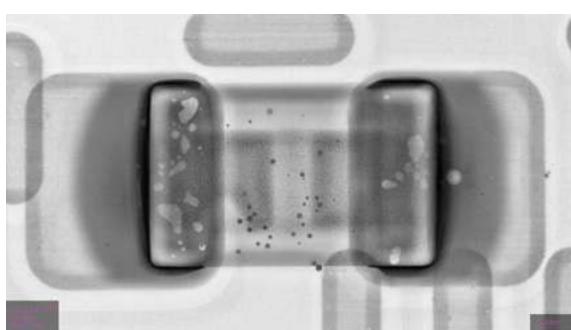
Fluoroscopic Image
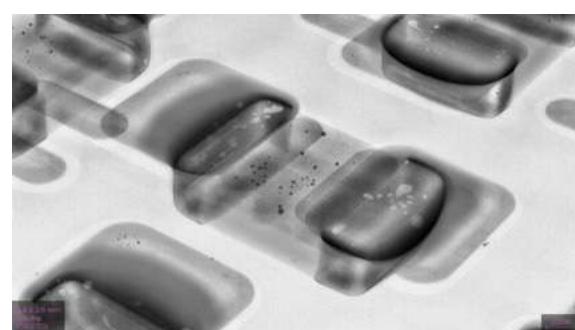
Fluoroscopic Image

LAN Connector
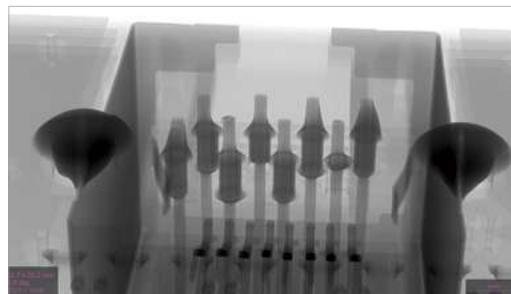
Fluoroscopic Image
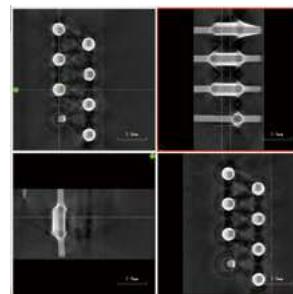
MPR Image Scanning
Region = 9.5 mm


VR Image

Insulated-Gate Bipolar Transistor
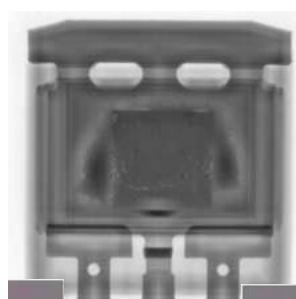
Fluoroscopic Image
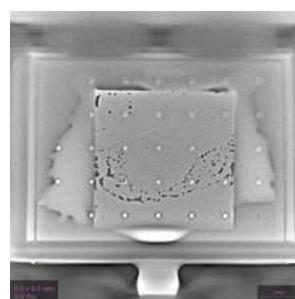
Cross-Sectional Image
Scanning Region = 8 mm

Fluoroscopic Image

Others

IC with terminal defect

Terminal defect

Fluoroscopic Image

Connector

Fluoroscopic Image

**18650 Lithium-Ion Battery**

Fluoroscopic Image

Optional Software

VGSTUDIO™
## Voxel Analysis and
Visualization Software

The VGSTUDIO software uses the volume rendering (VR) technique to display three-dimensional images from cross-section images obtained using X-ray CT imaging. It includes functionality for creating basic animation and simple measurements.
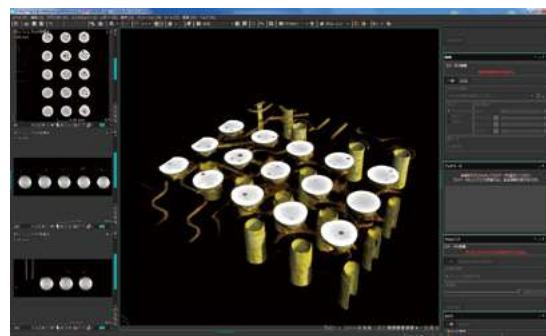
Xslicer SMX-6010

Specifications

Model	Xslicer SMX-6010
Spatial Resolution	1 µm (JIMA chart resolution)
Maximum Sample Size	470 × 420 × 100 mm, max. 5 kg
Fluoroscopic Inspection Stroke	X: 460 mm, Y: 410 mm, Z: 100 mm, ±180° rotation, 60° tilt
CT Scan Range	X: 350 mm, Y: 350 mm
Laminographic Angle (CT Scan Angle)	45° or 60°
X-Ray Output	Max. tube voltage: 160 kV, Max. tube current: 100 µA, Rated Output: 16 W
Detector	Flat panel detector
Fluoroscopy FOV (on Carbon Plate)	0.75 mm (vertical) × 1.3 mm (horizontal) to 21 mm (vertical) × 38 mm (horizontal)
CT FOV (on Carbon Plate)	3 to 30 mm (given 45° laminographic angle) / 3 to 14 mm (given 60° laminographic angle)
Power Requirements	200 V AC ± 10 %, 1.5 kVA (ground resistance 100 Ω max.)
Weight	Approx. 2,450 kg
Operating Environment Conditions	Ambient temperature: 15 to 30 °C, Ambient humidity: 35 to 80 % (no condensation)
External Leakage Dose	1 µSv/h max.

Size Layout and Dimensions (units: mm)

(Min. 450)

Recommended maintenance space: At least 3,150 mm

1600

384

Recommended maintenance space: At least 3,300 mm

(1150)~(1350)

1880~(1910)

1520

280

22

1760

(100)~(150)
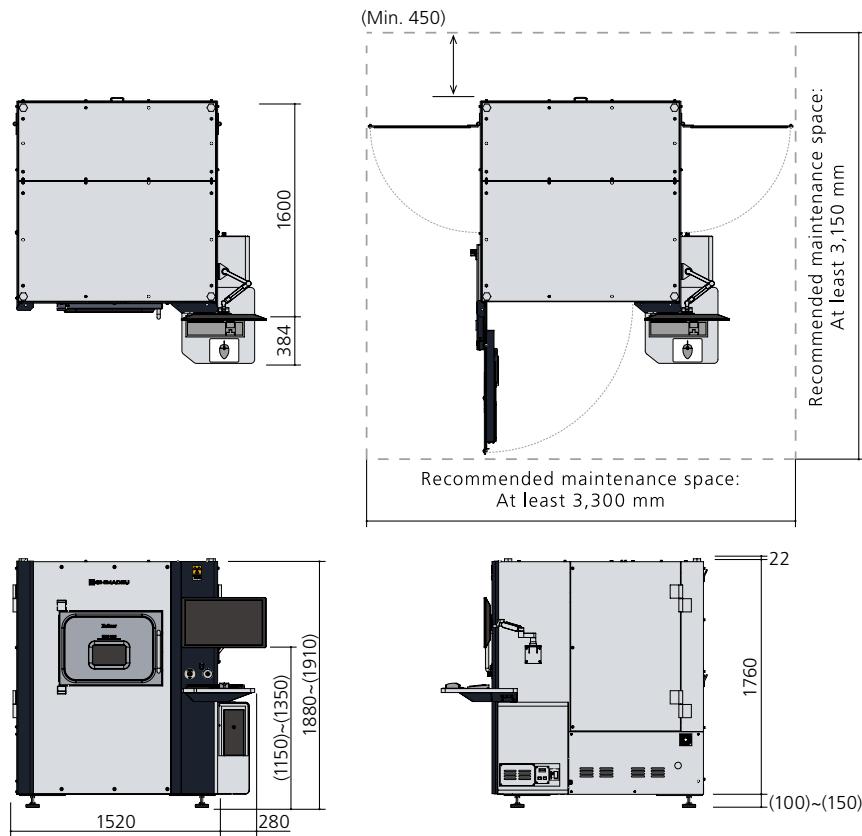
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VGSTUDIO is a trademark of Volume Graphics Gmbh.

SHIMADZU

Shimadzu Corporation

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